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APR 10 2006

Attorney Docket: 081468-0306781
Client Reference: P-0381.010-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
JOERI LOF ET AL.

Confirmation Number: 5288

Application No.: 10/705,805

Group Art Unit: 2851

Filed: November 12, 2003

Examiner: Peter B. Kim

Title: LITHOGRAPHIC APPARATUS AND DEVICE MANUFACTURING METHOD

* * * * *

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATION OF FACSIMILE TRANSMISSION
UNDER 37 C.F.R. §1.8

I hereby certify that the following papers are being facsimile transmitted to the
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SECOND REQUEST FOR RETURN OF PTO-1449 FORMS

PILLSBURY WINTHROP SHAW PITTMAN LLP

Jean-Paul G. Hoffman
Registration No. 42663
Telephone: (703) 770-7794
Facsimile: (703) 770-7901

Date: April 10, 2006

P.O. Box 10500
McLean, VA 22102
Customer No.: 00909

TOTAL PAGES: 7 pages total (including cover page)

(Certification of Facsimile Transmission—page 1)

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SECOND REQUEST FOR RETURN OF PTO-1449

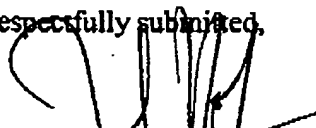
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicants respectfully point out that the Notice of Allowance, dated March 8, 2006, was issued the same day the attached Request for Return of Initialed PTO-1449 forms was filed. This Request was filed for the return of the PTO-1449 forms, which were filed on November 12, 2003, as indicated on the attached postcard receipt, which have not been returned to the Applicants initialed as considered by the Examiner.

Applicants respectfully request that the Examiner initial, sign and date the references on the attached PTO-1449 forms dated November 12, 2003, and return the forms to the undersigned. If there is any fee due for the return of these forms, please charge deposit account 03-3975, under Order No. 081468-0306781. Also, any overpayments should be credited to that account as well.

Respectfully submitted,



Date: April 10, 2006

Jean-Paul G. Hoffman
Registration No. 42663
PILLSBURY WINTHROP SHAW PITTMAN LLP
P.O. Box 10500
McLean, VA 22102
(703.) 770.7797
Customer No. 00909

and

Attorney Docket: 081468-0306781
Client Reference: P-0381.010-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
JOERI LOF ET AL.



Confirmation Number: 5288

Application No.: 10/705,805

Group Art Unit: 2851

Filed: November 12, 2003

Examiner: Peter B. Kim.

Title: LITHOGRAPHIC APPARATUS AND DEVICE MANUFACTURING METHOD

REQUEST FOR RETURN OF PTO-1449

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicants respectfully request that the Examiner return an initialed copy of the PTO-1449 form that was filed on November 12, 2003. A copy of the PTO-1449, the cited references, and the stamped USPTO receipt are attached for the Examiner's convenience.

Applicants respectfully request that the Examiner initial, sign and date the references on the attached PTO-1449 form dated November 12, 2003, and return the form to the undersigned.

Respectfully submitted,

A handwritten signature in black ink, appearing to read "JP Hoffman", written over a horizontal line.

Date: March 8, 2006

Jean-Paul G. Hoffman
Registration No. 42663
PILLSBURY WINTHROP SHAW PITTMAN LLP
P.O. Box 10500
McLean, VA 22102
(703.) 770.7797
Customer No. 00909

FORM PTO-1449 (modified)
To: U.S. Department of Commerce
(PW FORM PAT-1449)
Patent and Trademark Office

INFORMATION DISCLOSURE STATEMENT BY APPLICANT



App. No.	306781	P-0381.010-US
Applicant: Joeri LOF et al.		
Appin. No.: Unknown		
Filing Date: November 12, 2003		
Examiner: Unknown		Group Art Unit: Unknown

Date: November 12, 2003 Page 1 of 3

U.S. PATENT DOCUMENTS

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR 3,573,975	04/1971	Draka et al.	117	212	
	BR 3,648,587	03/1972	Stevens	85	44	
	CR 4,346,184	08/1982	Tabarelli et al.	430	311	
	DR 4,396,705	08/1983	Akayama et al.	430	326	
	ER 4,480,910	11/1984	Takanashi et al.	355	30	
	FR 4,509,852	04/1985	Tabarelli et al.	355	30	
	GR 5,040,020	08/1991	Rauschenbach et al.	355	53	
	HR 5,121,256	06/1982	Corle et al.	359	664	
	IR 5,610,683	03/1987	Takanashi	355	53	
	JR 5,715,039	02/1998	Fukuda et al.	355	53	
	KR 5,825,043	10/1998	Suwa	250	548	
	LR 5,900,354	05/1999	Batchelder	430	395	
	MR 6,191,429	02/2001	Suwa	250	548	
	NR 6,560,032	05/2003	Hatano	359	656	

FOREIGN PATENT DOCUMENTS

	Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
					Enclosed	No	Enclose	No
	OR WO 99/49504	09/1999	PCT	Fukami et al.	X		X	
	PR EP 0023233	02/1981	Europe	Tabarelli et al.	X			
	QR EP 0418427	03/1991	Europe	Miyake	X		X	
	RR EP 1038511	08/2000	Europe	Murakimi et al.	X		X	
	SR DD 224448	07/1985	German	Hesse et al.		X		
	TR DD 242880	02/1987	German	Kuch		X		
	UR FR 2474708	07/1981	France	Letellier		X		
	VR JP 62-065326	03/1987	Japan	Moriuchi	X			
	WR JP 62-121417	06/1987	Japan	Nakazawa	X			
	XR JP 63-157419	06/1988	Japan	Nakasugi	X			

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

YR	EP Search Report for EP 02257938 dated September 25, 2003			
ZR	M. Switkes et al., "Immersion Lithography at 157 nm", MIT Lincoln Lab, Orlando 2001-1, December 17, 2001			
AAR	M. Switkes et al., "Immersion Lithography at 157 nm", J. Vac. Sci. Technol. B., Vol. 19, No. 6, November/December 2001, pp. 2353-2356			
BBR	M. Switkes et al., "Immersion Lithography: Optics for the 50 nm Node", 157 Anvers-1, September 4, 2002			

Examiner

Date Considered:

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

FORM PTO-1449 (modified)
To: U.S. Department of Commerce
(PW FORM RAT-1449)
Patent and Trademark Office

App.
Dkt. No.

MS

Client Ref.

306781

P-0381.010-US

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Applicant: Joeri LOF et al.

Appl. No.: Unknown

Filing Date: November 12, 2003

Examiner: Unknown

Group Art Unit: Unknown

Date: November 12, 2003

Page

2

of

3

U.S. PATENT DOCUMENTS

Examiner's Initials	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	CCR 6.603.130	08/2003	Bisschops et al.	250	492.1	
	DDR 6.633.365	10/2003	Suenaga	355	53	
	EER 2002/0163629	11/2002	Switkes et al.	355	53	
	FFR 2003/0123040	07/2003	Almog	355	69	
	GGR 2003/0174408	09/2003	Rostalski et al.	359	642	
	HHR					
	IIR					
	JJR					
	KKR					
	LLR					
	MMR					
	NNR					
	OOR					
	PPR					

FOREIGN PATENT DOCUMENTS

	Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
					Enclosed	No	Enclose	No
	OOR JP 04-305915	10/1992	Japan	Ozeki et al.	X			
	RRR JP 04-305917	10/1992	Japan	Ozeki et al.	X			
	SSR JP 06-124873	05/1994	Japan	Takanashi	X		X	
	TTR JP 07-220990	08/1995	Japan	Fukuda et al.	X			
	UUR JP 10-226661	08/1998	Japan	Kurokawa	X			
	VVR JP 10-255319	09/1998	Japan	Suenaga et al.	X			
	WWR JP 10-303114	11/1998	Japan	Suwa	X		X	
	XXR JP 10-340846	12/1998	Japan	Kudo	X		X	
	YYR JP 2001-091849	04/2001	Japan	Aizaki et al.	X			
	ZZR							

OTHER (including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

AAAR	B.J. Lin, "Drivers, Prospects and Challenges for Immersion Lithography", TSMC, Inc., September 2002			
BBBR	B.J. Lin, "Proximity Printing Through Liquid", IBM Technical Disclosure Bulletin, Vol.20, No. 11B, April 1978, p. 4897			

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Group Art Unit: Unknown

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Page

3

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5

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	CCC					
	DDD					
	EEE					

FOREIGN PATENT DOCUMENTS

EEE										English Abstract		Translation Readily Available		
FOREIGN PATENT DOCUMENTS														
		Document Number	Date MM/YYYY	Country	Inventor Name						Enclosed	No	Enclose	No
	FFF													
	GGG													

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

HHH	B.J. Lin, "The Paths To Subhalf-Micrometer Optical Lithography", SPIE Vol. 822, Optical/Laser Microlithography (1988), pp. 256-268				
IIIR	G.W.W. Stevens, "Reduction of Waste Resulting from Mask Defects", Solid State Technology, August 1978, Vol. 21 008, pp. 68-72				
JJJR	S. Owa et al., "Immersion Lithography: its potential performance and issues", SPIE Microlithography 2003, 5040-186, February 27, 2003				
KKK	S. Owa et al., "Advantage and Feasibility of Immersion Lithography", Proc. SPIE 5040 (2003)				
LLLL	Nikon Precision Europe GmbH, "Investor Relations - Nikon's Real Solutions", May 15, 2003				
MMM	H. Kawata et al., "Optical Projection Lithography using Lenses with Numerical Apertures Greater than Unity", Microelectronic Engineering 9 (1989), pp. 31-35				
NNN	J.A. Hoffnagle et al., "Liquid Immersion Deep-Ultraviolet Interferometric Lithography", J. Vac. Sci. Technol. B, Vol. 17, No. 6, November/December 1999, pp. 3306-3309				
OOO	B.W. Smith et al., "Immersion Optical Lithography at 193nm", FUTURE FAB International, Vol. 15, July 11, 2003				
PPP	H. Kawata et al., "Fabrication of 0.2µm Fine Patterns Using Optical Projection Lithography with an Oil Immersion Lens", Jpn. J. Appl. Phys. Vol. 31 (1992), pp. 4174-4177				
QQQ	G. Owen et al., "1/8µm Optical Lithography", J. Vac. Sci. Technol. B, Vol. 10, No. 6, November/December 1992, pp. 3032-3035				
RRR					
SSS					
TTT					
UUU					
VVV					
WWW					
XXX					
YYY					

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PTO RECEIPT Agency Docket: 081468-0306781

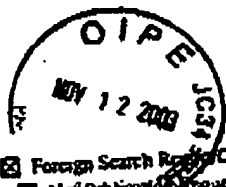
Appy: Jack Baruffa/PH-K.S. Hines

Appin. No: 1,000 Date: November 12, 2003

Inventor(s): Joeri LOF et al.

Title: LITHOGRAPHIC APPARATUS AND DEVICE
MANUFACTURING METHOD

- ☐ Preliminary Amendment ☒ Application Data Sheet
☐ Appendix ☒ Utility/Design/Provisional
☒ 19 No. of Pages Application (Spec + Claim(s) + Abstract)
☐ No. of Pages Separate Power of Attorney
☒ 27 No. of Numbered Claims Only
☐ Declaration (___ of pages)
☐ Assignment ☐ Cover Sheet
☒ 1 No. of Priority Documents
☒ 2 No. of Sheets of Drawings (Figs) (1-4)
☐ IDS ☐ Appendix for Cited Appl(s) ☒ Foreign Search Report/OA
☒ PTO-1449 ☒ Cited Documents ☐ Nonpublication Request
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CDC-255A 7405

PTO RECEIPT Agency Docket: 081468-0306781

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